Docket No.: 42P17301



In Re the Application of:

WANG YUEH, ET AL.

Application No.: 10/687,288

Filed: October 15, 2003

For: METHODS AND COMPOSITIONS FOR

REDUCING LINE WIDE ROUGHNESS

Examiner: Daborah Chacko Davis

Art Group: 1756

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

In accordance with the duty of disclosure, enclosed is a copy of IDS Citation Form PTO/SB/08 or PTO-1449, together with copies of the documents cited on that form, except for copies not required to be submitted (e.g., copies of U.S. patents and U.S. published patent applications need not be enclosed). This IDS and IDS Citation Form are being submitted concurrently with the Request for Continued Examination. It is respectfully requested that the cited references be considered and that the enclosed copy of PTO/SB/08 be initialed by the Examiner to indicate such consideration and a copy thereof returned to applicant(s).

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The submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made in the subject application and is not to be construed as an admission that the information cited in this statement is material to patentability.

Please charge any fees due to Deposit Account 02-2666. A duplicate copy of the Fee Transmittal (PTO/SB/17) is enclosed for this purpose.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Date: August 10, 2006

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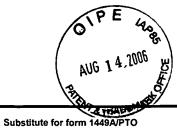
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

of **Sheet** 1 1

Complete if Known		
Application Number	10/687,288	
Filing Date	October 15, 2003	
First Named Inventor	Wang Yueh	
Art Unit	1756	
Examiner Name	Daborah Chacko Davis	
Attorney Docket Number	42P17301	

	NON PATENT LITERATURE DOCUMENTS		
Examiner Initials*	Cite No.¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
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Examiner	Date
Signature	Considered

^{*}Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication.

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